

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appln. No: To Be Assigned  
Applicant: Eiichi Ito et al.  
Filed: Herewith  
Title: ELECTRON BEAM EXPOSURE METHOD AND ELECTRON BEAM  
EXPOSURE SYSTEM  
TC/A.U.:  
Examiner:  
Confirmation No.:  
Docket No.: AOY-3989US

**PRELIMINARY AMENDMENT**

Mail Stop PCT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Prior to examination, please amend the above-identified application as follows:

- ☒ **Amendments to the Title** begin on page 2 of this paper.
- ☒ **Amendments to the Specification** begin on page 3 of this paper.
- ☐ **Amendments to the Claims** are reflected in the listing of claims which begins on page of this paper.
- ☐ **Amendments to the Drawings** begin on page of this paper and include an attached replacement sheet(s).
- ☐ **Amendments to the Abstract** are on page of this paper. A clean version of the Abstract is on page of this paper.
- ☐ **Remarks/Arguments** begin on page of this paper.

**Amendments to the Title:**

Please replace the title with the following:

~~ELECTRON BEAM EXPOSURE METHOD AND ELECTRON BEAM EXPOSURE SYSTEM~~  
ELECTRON BEAM EXPOSURE METHOD AND ELECTRON BEAM EXPOSURE APPARATUS